

09-20-01

2812 #2



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Martin, Kirk
Assignee: Nisene Technology Group
Title: Method And Apparatus For Etching A Semiconductor Die
Serial No.: 09/902,931 Filing Date: July 10, 2001
Examiner: Unknown Group Art Unit: Unknown
Docket No.: M-11706 US

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**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying form PTO-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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Respectfully submitted,

Robert D. Wasson
Attorney for Applicant(s)
Reg. No. 40,218

LAW OFFICES OF
SKJERVEN MORRILL
MacPHERSON LLP
3 EMBARCADERO CENTER
SUITE 2800
SAN FRANCISCO, CA 94111
(415) 217-6000
FAX (415) 434-0646